

# MECHATRONIC SYSTEMTECHNIK UNVEILS PROPRIETARY CALOTTE LOADER MWL.CS

Jan 20, 2021

Villach, Austria, 20 Jan 2021 — mechatronic systemtechnik, a leading global supplier of automation equipment for semiconductor wafer handling, today announces the availability of the mWL.cs mechatronic calotte loader. A fully automated stand-alone system for transferring wafers between cassettes and calottes, the mWL.cs provides integrated device manufacturers (IDMs) an opportunity to increase yield and improve process traceability at a high throughput.

Evaporation process tools often utilize spherical carriers and rings to meet uniformity and defectivity targets. However, the design of these tools has made it challenging to introduce automated wafer handling in this step of the manufacturing process. IDMs invariably default to manual wafer loading, which has resulted in yield degradation and an increased risk for misprocessing.

“Automating the wafer loading and unloading system for evaporation type metal deposition is a step that bears much potential,” shared Stefan Detterbeck, Sales Director. “By eliminating human error from the equation, our system enables manufacturers to achieve higher yield and reduce damage to wafers. Enhanced process traceability also supports quality improvement measures to meet the conformity requirements of critical customer industries.”



Key features of the mWL.cs mechatronic calotte loader include:

- ☒ Superior handling accuracy and repeatability — hand-off position measurement and auto-teaching capabilities (<50µm)
- ☒ Improved process traceability — host notification of Wafer ID, Cassette ID, Segment ID, and position in the segment
- ☒ Redundancy — 2 loading areas for continuous processing
- ☒ Impressive transfer times — high throughput of up to 240 wph that enables ROI within two years
- ☒ Dual size handling — customizable to handle 4", 6", 8", or 6" & 8" (dual size)
- ☒ Small footprint — less than 7 m<sup>2</sup>

A specialist in fully automated handling systems for non-standard substrates and handling requirements, mechatronic recognizes and addresses the semiconductor industry's need for the handling of ultra-sensitive substrates used in modern new wafer fabrication technologies. The company's deep expertise and proprietary technologies provide manufacturers with safe, reliable systems that handle non-standard substrates with ease and confidence.

For more information, please visit [www.mechatronic.at](http://www.mechatronic.at).

###

### **About mechatronic systemtechnik**

mechatronic systemtechnik, headquartered in Villach, Austria, is a leading global supplier of automation equipment for semiconductor wafer handling. Founded in 1998, the company specializes in addressing the industry's needs for reliable, safe, and fully automated handling of non-standard substrates — including stacked, thin, or warped wafers, and also eWLP, MEMS, TAIKO, bumped, and film frames. Through a modular approach, mechatronic offers its customers cost-efficient handling systems that feature its proprietary technology. These solutions are capable of accommodating a wide range of substrate types and their specific characteristics. Major OEMs and fabrication plants across the globe rely on mechatronic's unique solutions for some of their most complex handling needs.



For more information, please visit [www.mechatronic.at](http://www.mechatronic.at) or connect with us on social media:

LinkedIn: [www.linkedin.com/company/mechatronic-systemtechnik](http://www.linkedin.com/company/mechatronic-systemtechnik)

YouTube: [www.youtube.com/user/MechatronicAustria](http://www.youtube.com/user/MechatronicAustria)

mechatronic systemtechnik is a subsidiary of Accuron Industrial Technologies.

Editorial Contact:

Ms Gracine Wee | e: [gracine@redbugpr.com](mailto:gracine@redbugpr.com) | t: +65 6220 4787

673 South Milpitas Blvd.  
Milpitas, CA 95035, USA

[semihq@semi.org](mailto:semihq@semi.org)

©2022 SEMI All rights reserved.  
[Terms of Use](#) | [Privacy Policy](#)

ICP number of 沪ICP备06022522号

